



Initial Review  
BOX AF

RESPONSE UNDER 37 CFR 1.116 - EXPEDITED  
PROCEDURE - EXAMINING GROUP 1112

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GROUP 1100

#9/B  
(N.E.)  
#14/D

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of:

Takeshi FUKUNAGA et al.

Serial No. 08/519,420 -

Filed: August 25, 1995 -

For: A METHOD OF MANUFACTUR-

ING A SEMICONDUCTOR DEVICE

INCLUDING LASER IRRADIATION

FOLLOWED BY THERMAL

ANNEALING

) Examiner M. Padgett

) Art Unit 1112

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) Docket No. 0756-1398

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, BOX AF, Washington, D.C. 20231, on December 3, 1996.

*Deborah J. Tomme*  
Deborah T. Tomme

AMENDMENT AFTER FINAL REJECTION

Honorable Assistant Commissioner for Patents

BOX AF

Washington, D.C. 20231

Sir:

In response to the final rejection Office Action mailed September 3, 1996, please amend the above identified application as follows.

Do NOT enter Mr. Padgett - 12/14/96